

Contents

Preface	xi
1 A Brief Historical Overview	1
1.1 Scanning Electron Microscopy	1
1.1.1 The Beginnings	1
1.1.2 The Need for Added Capabilities	3
1.2 The Development of Imaging in a Gas Environment	6
1.2.1 Overcoming the Limits of Conventional SEM	6
1.2.2 Leaps and Bounds	9
2 Principles of SEM	17
2.1 Introduction	17
2.1.1 Why Use An Electron Beam?	17
2.1.2 The SEM Column	19
2.1.3 Why Do We Need a Vacuum System?	19
2.2 Electron Sources	20
2.2.1 Thermionic Emission Sources	21
2.2.2 Field Emission Sources	22
2.3 Electron Optics	23
2.3.1 Lenses	23
2.3.2 Lens Aberrations	26
2.4 Signals and Detection	31
2.4.1 Primary Electrons and the Interaction Volume	33
2.4.2 Backscattered Electrons	39
2.4.3 Secondary Electrons	41
2.4.4 X-ray Radiation	45
2.4.5 Cathodoluminescence	47
2.5 Practical Aspects of Electron Beam Irradiation	48
2.5.1 Radiation Damage	48

2.5.2	Minimising Specimen Charging – Low-Voltage SEM	50
2.5.3	Increasing Surface and Bulk Conductivities	51
2.6	SEM in Operation	53
2.6.1	Building Up an Image	53
2.6.2	Magnification	53
2.6.3	Signal-to-Noise Ratio	54
2.6.4	Contrast	55
2.6.5	Adjusting the Contrast	56
2.6.6	Resolution	57
2.6.7	Depth of Field	59
2.6.8	Image Capture	60
3	General Principles of VP-ESEM: Utilising a Gas	63
3.1	Introduction	63
3.2	VP-ESEM Instrumentation	64
3.2.1	Typical Features	64
3.2.2	Primary Electron Scattering in VP-ESEM – the General Case	65
3.2.3	Units of Pressure	68
3.3	Signal Generation in a Gas	68
3.3.1	Introduction	68
3.3.2	Direct Collection of Electrons and Ions	69
3.3.3	Collection of Photons – the Gas Luminescence Signal	74
3.3.4	Detecting Indirect Electron and Ion Currents	78
3.4	Imaging with Water Vapour	81
3.4.1	Introduction	81
3.4.2	Thermodynamic Equilibria	81
3.4.3	Nonequilibrium Conditions	86
3.4.4	Practicalities of Stabilising Hydrated Specimens	87
4	Imaging and Analysis in VP-ESEM: The Influence of a Gas	93
4.1	Introduction	93
4.2	Background to Theoretical Calculations	94
4.2.1	Calculating the Mean Free Paths of Primary Electrons	94
4.2.2	Calculating Pressure-Dependent Variables	94
4.2.3	Estimating the ‘Useful’ Primary Electron Current	95
4.3	Which Gas?	98
4.3.1	Introduction	98

4.3.2	Usefulness of the Gas – Experimental Conditions	98
4.3.3	Ionisation and Excitation for Different Gases	99
4.3.4	Scattering of the Primary Electron Beam in Different Gases	101
4.4	Exploring the Gas Path Length	106
4.4.1	Introduction	106
4.4.2	Influence of GPL on the Skirt Radius	107
4.4.3	Gas Path Length and Useful Primary Electron Beam Current	108
4.4.4	Constraints on Reducing the Gas Path Length	109
4.4.5	Separating Gas Path Length from Working Distance	111
4.5	How Much Gas?	112
4.5.1	Introduction	112
4.5.2	Scattering of Primary Electrons as a Function of Pressure	114
4.6	X-ray Microanalysis in VP-ESEM	121
4.6.1	Introduction	121
4.6.2	Effects of Chamber Gas on X-ray Signals	121
4.6.3	Considerations for Minimising the Effects of the Gas	123
4.6.4	Post-Acquisition Methods to Correct for Scattering	126
5	Imaging Uncoated Specimens in the VP-ESEM	131
5.1	Introduction	131
5.2	Electronic Structure	132
5.2.1	The Energy Level Diagram	132
5.2.2	Conductors, Semiconductors and Insulators	133
5.3	Factors Affecting Secondary Electron Emission	135
5.3.1	Transport of Excited Electrons	135
5.3.2	Escape of Excited Electrons	137
5.4	The Influence of the Specimen on the System	137
5.4.1	The Effect of Charging – the General Case	137
5.4.2	Measuring Surface Potential	141
5.4.3	Conductive, Electrically Grounded Bulk Materials	141
5.4.4	Conductive, Electrically Isolated Materials	142
5.4.5	Nonconductive, Uncoated Materials	143
5.5	Time- and Temperature-Dependent Effects	145
5.5.1	Introduction	145
5.5.2	Conductivity and Some Time-Dependent Effects	145

5.5.3	Charge Traps and Thermal Effects	150
5.6	Imaging Soft Materials	151
5.6.1	Introduction	151
5.6.2	Choosing an Appropriate Primary Beam Energy	152
5.6.3	Radiation Damage	156
5.7	Effects of Ions on Imaging	158
5.7.1	Introduction	158
5.7.2	Consideration of the Concentration of Positive Ions	158
5.7.3	Ion Mobility Effects	159
5.7.4	An Additional Surface Potential	161
5.7.5	Electron–Ion Recombination and Signal Scavenging	162
5.7.6	Combating Excess Ions	163
5.8	Imaging with a Gas: Summary	164
6	A Lab in a Chamber – <i>in situ</i> Methods in VP-ESEM and Other Applications	169
6.1	Introduction	169
6.2	Nanocharacterisation of Insulating Materials	170
6.2.1	High-Resolution Imaging	170
6.2.2	Anti-Contamination in the VP-ESEM	171
6.2.3	Nanometrology	172
6.2.4	Utilising Novel Contrast Mechanisms	173
6.2.5	Transmitted Electron Signals – STEM and Wet STEM	178
6.3	<i>In situ</i> Experiments	181
6.3.1	Deformation and Failure	181
6.3.2	Low-Temperature Experiments	182
6.3.3	High-Temperature Experiments	186
6.3.4	Condensation and Evaporation of Water	189
6.3.5	Processes Using Electron Beam Gas Chemistry in the VP-ESEM	194
6.3.6	High-Pressure Experiments	196
6.4	Other Applications	198
6.4.1	Introduction	198
6.4.2	Biological Specimens	198
6.4.3	Liquids and Soft Materials	202
6.4.4	Hard/Soft Composites and Hard Materials	204
	Index	215